OKMETIC

Data management as a part of semiconductor production process development

Sustainable Manufacturing Launch March 5th 2020

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World's leading supplier of silicon wafers for most of the top 30 MEMS manufacturers

- Focusing on bonded SOI products and specialized 150-200 mm wafers
- Cutting-edge solutions to customers who are world's leading manufacturers



Net sales: 107 M€ Investments:

> 100 M€ (2017-2021) Employees: ~ 450

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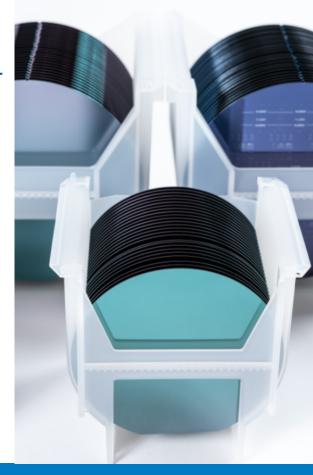
Headquarters and production in Finland with sales and technical applications support worldwide

> 800 square meter dedicated patterning line



Focusing on the niche markets of semiconductor industry

- Sensor industry (59% of net sales)
 - Okmetic is the market leader
 - Material for MEMS and other sensor applications
- Discrete & analog industry (41% of net sales)
 - Okmetic is a valued and reliable supplier
 - High resistivity and high voltage SOI materials



From sand to silicon chips

Edge rounding

Lapping

Acid/Caustic etching

CVD deposition (optional)

Wafer grinding (optional)

CMP polishing

Final cleaning



Quartz sand



Hyperpure polysilicon



Crystal growth



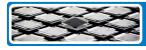
Ingot cutting, grinding, slicing



Silicon wafer processing



Wafer inspection and packaging



1000's of devices manufactured per wafer



Silicon wafer is the plate on which technology is built



Data management contains

- Tool data integration
 - Silicon Wafer line tools vary greatly in applicability
- Ship to control
 - Control of statistical outliers from shipped material
- Statistical process control
 - Application through six sigma approach
- Effective data mining
 - Statistical analysis of product data, primarily to support process development



Advanced data management targets in semiconductor materials

Enhanced process control

Improved yield, providing
 Profitability
 Reduced environmental impact

Reduced product variation

 Reduction / elimination of customer process incursions with Better customer satisfaction
 Reduced need for corrective actions

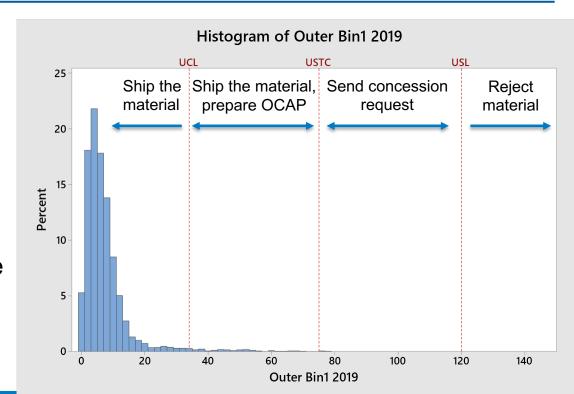
Provision of detailed product data for customers

Enabling customers to further improve their processes,
 Building trust
 Improving customer yields
 Enhancing reliability of customer products (ppb or even ppt targets)



Ship-to-Control (STC) in a nutshell

- The idea is the introduce different material quality decision zones based on statistical calculations.
- The precise position of decision zones are not unambiguous
 - Zones may overlap
- Technical-economically viable accept / reject decision is not straightforward.



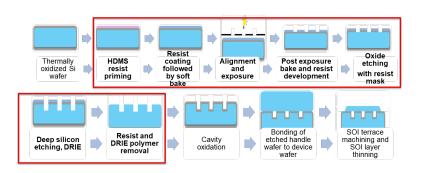
STC basics: Three sigma rule, alpha risk and P (false alarm)

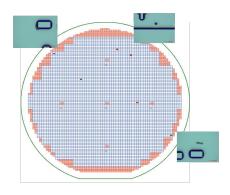
- False alarm probability 0.0027 0.9973
- Three sigma rule, generally required industry standard, means that ~0.27% of observations can be OOC even when there was no specific reason for the deviation.
- Alpha risk is the number which indicates the false alarm probability.
- For additional follow up items, control limits must be adjusted in order to keep the total alpha risk, alpha total, at 0.27%.
- These control limit settings apply only for stable processes. Real world processes include some acceptable drift
- Control limit settings CL = Mean ± 4 x Sigma is a simple and a good approximation when following multiple items simultaneously.

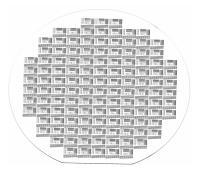
	Probability	False	
No	between	alarm	
controlled	LCL and	propability	
parameters	UCL (%)	(%)	t_crit
1	0.9973	0.2700	3.000
2	0.9946	0.5392	3.205
3	0.9919	0.8078	3.320
4	0.9892	1.0756	3.399
5	0.9866	1.3426	3.460
6	0.9839	1.6090	3.509
7	0.9813	1.8746	3.549
8	0.9786	2.1395	3.584
9	0.9760	2.4037	3.615
10	0.9733	2.6672	3.642
100	0.7631	23.6884	4.197
1000	0.0670	93.3026	4.692
10000	0.0000	100.0000	5.143
100000	0.0000	100.0000	5.560

Provision of detailed product data for customers: Sample case C-SOI®

For advanced products with embedded structures, wafer level and chip level data enables customer to analyse their device level data, and reject individual dies with observed anomalies







Examples of chip level data collected from C-SOI® process:

Automated optical microscopy (AVI)

Scanning acoustic microscopy (SAM)